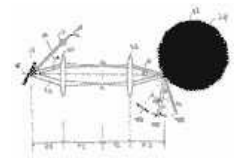


3 results for ((interferometer)/TI/AB/CLMS/DESC/ODES/OBJ/ADB/ICLM/KEYW/TX AND (laser)/TI/AB/CLMS/DESC/ODES/OBJ/ADB/ICLM/KEYW/TX AND (polyhed+ or octahed+)/TI/AB/CLMS/DESC/ODES/OBJ/ADB/ICLM/KEYW/TX AND (mirror+)/TI/AB/CLMS/DESC/ODES/OBJ/ADB/ICLM/KEYW/TX AND (opaque)/TI/AB/CLMS/DESC/ODES/OBJ/ADB/ICLM/KEYW/TX) AND (G01B-009/02)/IPC - Collection: FAMPAT

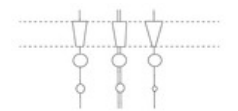
#	 Title	Publication number	Publ. date	Applicant/Assignee
1.	Process and apparatus for a wavelength tuned light source	EP2011434	2009-01-07	 MASSACHUSETTS GENERAL HOSPITAL

An apparatus comprises an arrangement (2) emitting an electromagnetic radiation. The arrangement is capable of modifying a mean frequency of a spectrum of the electromagnetic radiation substantially continuously over time at a tuning speed that is greater than 100 terahertz per millisecond.



2.	Characterizing tsv microfabrication process and products	WO2014/116878	2014-07-31	 RUDOLPH TECHNOLOGY RUDOLPH TECHNOLOGIES
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A method for characterizing a microfabrication process and the product thereof is described. A substrate having TSV's formed therein is assessed by determining the geometries and positions of the top and bottom ends of a TSV. Individual TSV's as well as the entire pattern of TSV's formed in a substrate may be assessed.



3.	Inspection device and method	JP2007171145	2007-07-05	 CANON
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PROBLEM TO BE SOLVED: To provide an inspection device and method capable of inspecting (detecting) precisely a foreign matter existing in an optical material, in a short time, by simple constitution.
SOLUTION: This inspection device for detecting the foreign matter existing in the optical material, has a light source part for emitting a light beam and for changing a frequency of the light beam, a light guide means for guiding the light beam emitted from the light source part to a reference **mirror** face and the optical material, and a computing means for computing three-dimensional position coordinates of the foreign matter existing in the optical material, based on an interference light beam of a light beam reflected from the reference **mirror** face with a light beam reflected from the foreign matter existing in the optical material.
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